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M. Brown
PATENT
2342-0107P
1/28/03

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Mitsuhiro HIRANO Conf. No.: 3165
Appl. No.: 08/813,200 Group: 2814
Filed: March 7, 1997 Examiner: S. Rao
For: SUBSTRATE PROCESSING APPARATUS WITH LOCAL EXHAUST
FOR REMOVING CONTAMINANTS

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AMENDMENT

Honorable Commissioner for Patents
Washington, D.C. 20231

January 16, 2003

Sir:

In response to the Office Action dated July 16, 2002, the period for reply extended three (3) months to January 16, 2003, the following amendments and remarks are respectfully submitted in connection with the above-identified application.

IN THE CLAIMS:

Please replace claims 11 and 16 with the following amended claims: Please note that claims 11 and 16 are presented below in their amended form. They are further presented as an Attachment to the Amendment whereby the amendments to the claims are outlined using the conventional method of bracketing and underlining.

11. (Six Times Amended) A substrate processing apparatus comprising:

a substrate processing chamber for processing a substrate;
a load lock chamber;
a gas supply for supplying gas into said load lock chamber;

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